

Customer No.: 31561
Docket No.: 12739-US-PA
Application No.: 10/710,698

REMARKS

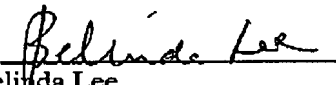
In response to the Office Action, mailed on October 15, 2007, a complete listing of all of the claims is presented herewith. Applicants would like to elect Group III, claims 8-15, drawn to an apparatus and a process for physical vapor deposition utilizing a rotating magnetic device with planarly- and axially-symmetric magnets, classified in class 204, subclass 298.22 and 192.25 respectively. Please cancel Groups I and II, claims 1-3 and claims 4-7, respectively drawn to an apparatus for physical vapor deposition including a magnetron device where magnetic poles are reversed in situ, classified in class 204, subclass 298.16, and a process for physical vapor deposition including a magnetron device where two deposition processes are used to define one deposition cycle classified in class 204, subclass 192.12, without waiver, prejudice or disclaimer.

If the Examiner believes that a telephone conference would expedite the examination of the above-identified patent application, the Examiner is invited to call the undersigned.

Date :

Nov. 14, 2007

Respectfully submitted,


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